CLAIMS

- An interface apparatus comprising:
 tester communicating means for communicating with a tester; and
 contactless communications means for communicating a test signal with a terminal of a
 device under test without physically contacting said terminal.
- 2. The apparatus of claim 1, wherein said contactless communications means communicates a plurality of test signals with a plurality of terminals of said device under test without physically contacting said terminals.
- 3. The apparatus of claim 2, wherein said contactless communications means comprises a plurality of conductive traces.
- 4. The apparatus of claim 3, wherein each of said traces are electromagnetically coupleable to conductive structures on said device under test.
- 5. The apparatus of claim 1 further comprising means for providing power to said device under test.
- 6. The apparatus of claim 1 further comprising means for controlling contactless communications with said device under test.
- 7. An interface apparatus comprising: electrically conductive elements connectable to a tester; and electrically conductive structures disposed to be contactlessly coupleable to a device under test.
- 8. The apparatus of claim 7, wherein said conductive structures are electromagnetically coupleable to said device under test.

- 9. The apparatus of claim 7 further comprising a transmitter configured to transmit test signals on at least one of said conductive structures.
- 10. The apparatus of claim 7 further comprising a receiver configured to receive a test signal induced on at least one of said conductive structures.
- 11. The apparatus of claim 7 further comprising a transceiver configured to transmit test signals on at least one of said conductive structures and to receive a test signal induced on at least one of said conductive structures.
- 12. The apparatus of claim 7 further comprising at least one probe disposed to provide power to said device under test.
- 13. The apparatus of claim 7 further comprising a substrate, wherein said electrically conductive structures are disposed on said substrate to correspond to conductive structures on said device under test.
- 14. The apparatus of claim 13 further comprising circuitry configured to control communications with said device under test.
- 15. The apparatus of claim 7, wherein said electrically conductive structures are disposed to communicate contactlessly a single signal received from said tester to a plurality of devices under test.
- 16. A semiconductor wafer comprising:
 - a plurality of dies each comprising functional circuitry; and
- electrically conductive structures configured to contactlessly receive test signals for testing said functional circuitry.
- 17. The semiconductor wafer of claim 16, wherein each die comprises a set of said conductive structures.

- 18. The semiconductor wafer of claim 16, wherein each of said conductive structures in a set of said conductive structures are electrically connected to a plurality of said dies.
- 19. The semiconductor wafer of claim 16, wherein said conductive structures are electromagnetically coupleable to a tester interface device.
- 20. The semiconductor wafer of claim 16 further comprising a transmitter configured to transmit test signals on at least one of said conductive structures.
- 21. The semiconductor wafer of claim 20, wherein each of said dies comprises such a transmitter.
- 22. The semiconductor wafer of claim 16 further comprising a receiver configured to receive a test signal induced on at least one of said conductive structures.
- 23. The semiconductor wafer of claim 22, wherein each of said dies comprises such a receiver.
- 24. The semiconductor wafer of claim 16 further comprising a transceiver configured to transmit test signals on at least one of said conductive structures and to receive a test signal induced on at least one of said conductive structures.
- 25. The semiconductor wafer of claim 24, wherein each of said dies comprises such a transceiver.
- 26. The semiconductor wafer of claim 16 further comprising built in self test circuitry.

27. A semiconductor wafer comprising:

a plurality of dies each comprising functional circuitry and terminals; and means for receiving a test signal from a tester channel without physically contacting said tester channel.

- 28. The semiconductor wafer of claim 27 further comprising means for sending a test signal to a test channel without physically contacting said tester channel.
- 29. The semiconductor wafer of claim 27, wherein said means for receiving receives a plurality of test signals from a plurality of tester channels without physically contacting said plurality of tester channels.
- 30. The semiconductor wafer of claim 27 further comprising means for controlling communications with a plurality of said tester channels.

31. An interface apparatus comprising:

means for receiving a single signal from a tester; and

contactless communications means for communicating said single test signal with terminals of a plurality of devices under test without physically contacting said terminals.

32. An interface apparatus comprising:

means for receiving a plurality of signals from a tester for testing a first number of devices; and

contactless communications means for communicating said plurality of signals with terminals of a second number of devices without physically contacting said terminals,

wherein said second number is greater than said first number.

33. A method of making a semiconductor die, said method comprising:

providing a semiconductor wafer comprising a die; contactlessly transmitting said test data to said die; and testing said die with said test data.

34.	The method of claim 33	further comprising c	ontactlessly reading	from said die response
data ge	nerated by said die.			

35. A die made using the method of claim 33.